

2811

Docket No.: M4065.0477/P477  
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Kevin M. Devereaux

3 / 4 formal Drawings  
E. Ullis  
12-3-01

Application No.: 09/939,636

Group Art Unit: N/A

Filed: August 28, 2001

Examiner: Not Yet Assigned

For: METHOD AND APPARATUS FOR WAFER  
LEVEL TESTING OF SEMICONDUCTOR  
USING SACRIFICIAL ON DIE POWER  
AND GROUND METALIZATION

SUBMISSION OF FORMAL DRAWINGS

Commissioner for Patents  
Washington, DC 20231


RECEIVED  
NOV 29 2001  
ROOM 1000  
TOLSON

Dear Sir:

Submitted herewith is one set (five sheets, Figures 1-5) of formal drawings for filing in the above-identified Patent application. Kindly substitute the enclosed formal drawings for the informal drawings submitted with the originally filed application.

Dated: November 20, 2001

Respectfully submitted,

By   
Thomas J. D'Amico  
Registration No.: 28,371  
DICKSTEIN SHAPIRO MORIN &  
OSHINSKY LLP  
2101 L Street NW  
Washington, DC 20037-1526

(202) 828-2232  
Attorneys for Applicant